



**AMENDMENT UNDER CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1746**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Confirmation No.: 7420

Takaei SASAKI et al.

Group Art Unit: 1746

Serial No.: 10/706,944

Examiner: Michail Kornakov

Filed: November 14, 2003

Attorney Docket No.: 101136-00103

For: METHOD AND APPARATUS FOR DRY-ETCHING HALF-TONE PHASE-SHIFT FILMS, HALF-TONE PHASE-SHIFT PHOTOMASKS AND METHOD FOR THE PREPARATION THEREOF, AND SEMICONDUCTOR CIRCUITS AND METHOD FOR THE FABRICATION THEREOF

AMENDMENT UNDER 37 CFR §1.116

Mail Stop: AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Date: December 23, 2004

Sir:

In reply to the outstanding Office Action dated September 3, 2004, the period for response being extended one-month from December 3, 2004, to January 3, 2004, with the filing of the attached Petition for Extension of Time, please amend the application as shown on the following pages: